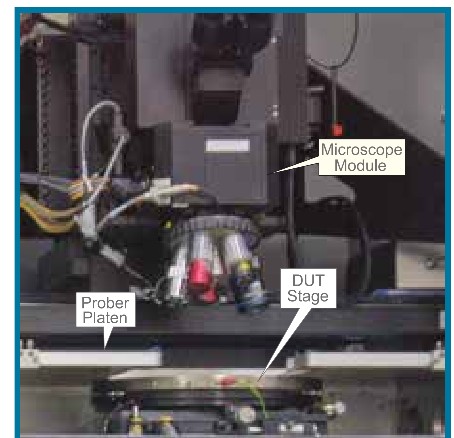
SEMICAPS 1100

UPRIGHT ANALYTICAL SYSTEM

Photo are for illustration only

Features

- For backside and frontside analysis of wafers, wafer parts and packaged devices
- Ultra-stable system compatible for probing FIB pads
- Compatible with third-party probe stations, probe cards and manipulators
- High resolution stage with 0.5 μm repeatability
- Aplanatic Refractive Solid Immersion Lens (ARSIL) option, currently probing 3nm nodes
- CAD interface option
- Techniques include a combination of:
  - Laser Timing Probe (LTP)
  - Scanning Optical Microscopy (SOM) with best sensitivity
    static: TIVA, OBIRCH
    dynamic: LADA, SDL
  - Photon Emission Microscopy (PEM) with various options for the InGaAs or Si-CCD camera
    Thermal Microscopy (THM) with InSb camera



300 mm Probe Station

SEMICAPS
Excellence In Innovation

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